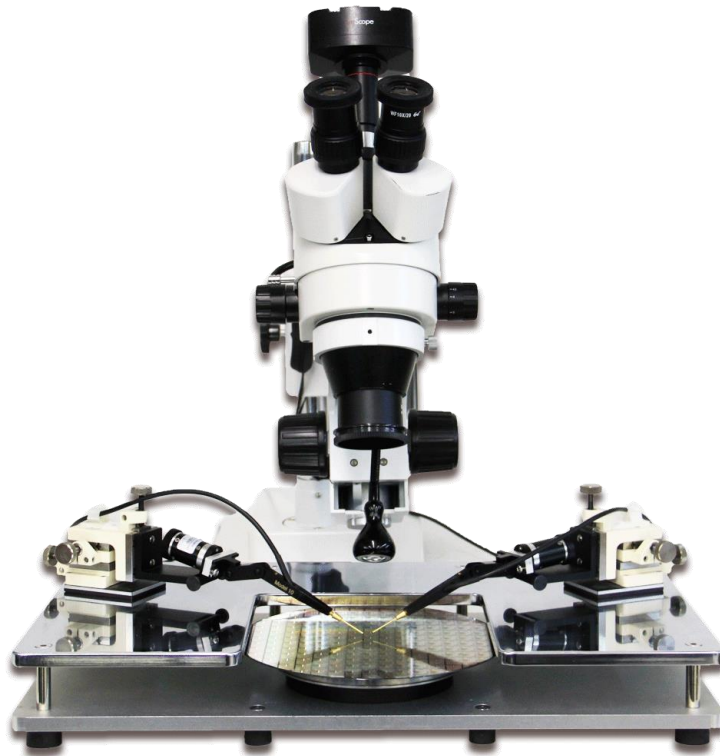


ES62X-CMPS Compact Manual Probe Station



1. Description

The ES62X-CMPS compact manual probe station is a rugged wafer probing solution designed for high reliability, compact size and low investment cost. It enables manual wafer level measurements up to 300 mm wafers. The probing station can also be used for TLP, HMM, HBM, LV-Surge, RF, S-parameter and DC-measurements. Micro positioners with vacuum as well as magnetic base can be attached. The chuck has a vacuum interface for the wafer and is electrically isolated. Multiple 4 mm connectors can be used to connect a voltage potential to the wafer backside.

The trinocular stereo microscope has 3.5X to 90X magnification and is equipped with a USB camera interface and a bright and ultra-long-life LED ring light.

2. Features

- Portable manual wafer probe station
- Electrically isolated chuck with vacuum interface and wafer backside potential connector
- Trinocular stereo microscope with 3.5 - 90 x magnification
- Includes 5 mp video camera and software
- Ultra long-life ring-style led ring light
- High reliability
- Low cost

3. Applications

- General probe station for TLP, HMM, HBM, LV-Surge, RF, S-parameter and DC-measurements
- Adaptive to different wafer sizes up to 300 mm
- Support magnetic PCB holder up to 180 X 130 mm



4. Specifications

ES62X-CMPS-TSM Trinocular Stereo Microscope



Parameters	Value	Unit	Comments
Magnification range	3.5x - 90x		
Zoom objective power	0.7x - 4.5x		
Eyepieces (DIN, 30mm)	WH10x20mm	dB	WH10x20mm high-eyepoint
Trinocular port	C-Mount or 23mm	dB	
Field of view	2-1/2	inch	
Optical working distance	Up to 8	inch	
Microscope stand	Double-arm boom stand		
Head movement	X-, Y-, and Z-axes		
Illumination type	Episcopic (reflected)		
Light source	LED ring light with rheostat	mm	
Power	110 - 240	V	
Dimensions	540 x 480 x 460	mm	
Weight	25	kg	

ES62X-CMPS-WPS Wafer Probe Station



Parameters	Value	Unit	Comments
Wafer Chuck diameter	170	mm	up to 300 mm wafers can be attached
Wafer Chuck Material	Stainless Steel		Mirror finish on top
Wafer Chuck Bias	4 mm connector		
Dimensions	500 X 300 X 100	mm	
Weight	About 14	kg	

ES62X-CMPS-MVP Miniature Vacuum Pump

Parameters	Value	Unit	Comments
Attainable Vacuum	-333	mbar	
Free Air Displacement	7	l/min	
Inlet O.D.	6	mm	
Outlet O.D.	6	mm	
Rated Voltage	120	VAC	
Power Consumption	14	W	
Life Expectancy	3000	h	
Dimensions	90 X 90 X 100	mm	
Weight	1	kg	

ES62X-CMPS-PCB Magnetic Flexible PCB Holder for Probe Station



Parameters	Value	Unit	Comments
Max PCB size	180 X 130 X 2	mm	
Dimensions	215 X 180 X 100	mm	
Weight	About 14	kg	

5. Ordering Information

Line	Part # or Option #	Description
1	ES62X-CMPS	Compact manual probe station (Including all 1.x sub items)
1.1	ES62X-CMPS-TSM	Trinocular stereo microscope including USB camera and LED light
1.2	ES62X-CMPS-WPS	Flexible manual wafer probe station
1.3	ES62X-CMPS-MVP	Miniature vacuum pump and accessories
1.4	ES62X-CMPS-PCB	Magnetic Flexible PCB holder

Customized probing design is available upon request